

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	81	optical correction lithography (spatial same frequency) flare	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2007/09/20 18:29
L2	4619	(optical lithography).ab.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2007/09/20 18:29
L3	21	l2 and l1	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2007/09/20 18:29
L4	55	("20030107770" "20030226951" "20040096883" "20040119036" "20040140418" "20040222354" "20040225488" "20040232313" "20050091633" "20050097500" "20050120327" "20050122500" "20050166174" "4926489" "5182718" "5308991" "5563702" "5594850" "5663893" "5680588" "5723233" "5737072" "5774222" "5888675" "6077310" "6078738" "6081659" "6090555" "6120952" "6223139" "6226781" "6243855" "6272236" "6285488" "6370679" "6372391" "6397165" "6405153" "6449749" "6453452" "6453457" "6470489" "6504644" "6519501" "6539331" "6611767" "6687041" "6757645" "6760473" "6765651" "6803554" "6806456" "6816302" "6828542" "6884984").PN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/09/20 18:35
L5	3720	optical same proximity same correction	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:35

EAST Search History

L6	389	I5 and (flare or (spatial same frequency))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:39
L7	168	I6 and aberrations	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:39
L8	141	I7 and phase	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:36
L9	44877	optical and lithography	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:36
L10	2614	I9 and (flare or (spatial same frequency))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:36
L11	663	I10 and aberration	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:36
L12	522	I11 and phase	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:36

EAST Search History

L13	240	l12 and (wavefront convolution)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:37
L14	123	l13 and ((point spread) same function)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:37
L15	2808	(700/108 716/2 716/4 716/20 716/21 703/13 382/145 355/67) and optical and correction	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:39
L16	2937	(700/108 716/2 716/4 716/20 716/21 703/13 382/145 355/67 703/2) and optical and correction	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:39
L17	281	l16 and (flare or (spatial same frequency))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:39
L18	92	l17 and aberration and phase	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:40
L19	478	(700/108 716/2 716/4 716/20 716/21 703/13 382/145 355/67 703/2) and (optical and correction). clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:44

EAST Search History

L20	49	l19 and (flare or (spatial same frequency)))".clm"	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:44
L21	1	l20 and (aberration and phase).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:44
L22	20	l20 and (aberration or phase).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:40
L23	231	(lithography and optical and correction).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:44
L24	42	l23 and (flare or (spatial same frequency)))".clm"	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:44
L25	0	l24 and (aberration and phase).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:45
L26	24	l24 and (aberration or phase).clm.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 18:45

EAST Search History

S1	32	("5644390" "5647027" "5680588" "6127071" "6223139" "6233059" "6263299" "6289499" "6303253" "6415421" "6425113" "6449387" "6453457" "6460997" "6487696").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/12 16:50
S2	0	S1 and (phase adj3 map)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/29 14:26
S3	0	S1 and (phase near3 map)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/29 14:26
S4	3	S1 and (point near3 function)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/29 14:26
S5	4	("6484300" "5619419").PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/08/31 18:35
S6	2	"6263299".PN.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 10:11
S7	29	("4652134" "5444265" "5502654" "5595861" "5663076" "5679598" "5682323" "5705301" "5723233" "5877045" "5900338" "5955227" "5998070").PN. OR ("6263299").URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 10:18
S8	18	S7 and (phase OR wavefront)	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 10:25
S9	88	(phase near2 map) and \$lithograph\$2	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 10:26

EAST Search History

S11	83	S9 and optic\$3	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 10:26
S12	84	"L8" and wavefront	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 10:26
S13	40	S11 and wavefront	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 10:26
S14	88	(phase near2 map) and \$5lithograph\$2	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 10:38
S15	42	S14 and optic	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 10:38
S16	5	"6831997".pn. "907902".ap.	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 12:29
S17	190	OPC and \$5lithograph\$2 and map and function	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 13:05
S18	189	S17 and correct\$4	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 12:35
S19	39	S18 and wavefront	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 12:29
S20	39	S18 and wavefront	US-PGPUB; USPAT; USOCR	OR	ON	2006/09/01 12:29
S21	143	S18 and intensity	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 13:04
S22	1	("6374396").PN.	USPAT; USOCR	OR	OFF	2006/09/01 18:01
S23	158	OPC and \$5lithograph\$2 and map and function and phase	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 13:05
S24	38	S23 and wavefront	US-PGPUB; USPAT; USOCR	OR	OFF	2006/09/01 13:05
S25	1	("7030997").PN.	USPAT; USOCR	OR	OFF	2006/09/01 14:08

EAST Search History

S26	2	((("6081658") or ("6289449")).PN.	USPAT; USOCR	OR	OFF	2006/09/01 14:08
S27	7	OPC and "phase map"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 16:06
S28	7	OPC and (phase adj map)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 16:06
S29	95	OPC and (phase same map)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 16:08
S30	13	S29 and wavefront	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 16:07
S31	14	OPC and (phase near3 map)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 16:08
S32	9	S31 not S30	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 16:08
S33	0	OPC and convolution and phase and aerial	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 18:02
S34	62	OPC and convolution and phase and aerial	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 18:56

EAST Search History

S35	2186	703/2	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 18:56
S36	12	"5153977"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2006/09/01 19:35
S37	2037	OPC.ab.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/04/03 14:30
S38	2	"20060095887"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/04/03 14:22
S39	1482	S37 and @ad<"20031027"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/04/03 14:31
S40	0	S39 and (high\$4order same abberation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/04/03 14:32
S41	0	S39 and (high\$4 same order same abberation)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/04/03 14:32
S42	72	S39 and (high\$4 same order)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/04/03 14:33

EAST Search History

S43	3	S42 and aberration	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/04/03 15:04
S44	1	("6862538").PN.	USPAT; USOCR	OR	OFF	2007/04/03 15:04
S45	2	"20050091013"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/04/09 13:27
S46	4	"7030997".pn. or "6374396".pn.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/04/13 16:25
S47	1	("6,548,312").PN.	USPAT; USOCR	OR	OFF	2007/04/13 16:45
S48	1352	(OPC and layout and mask)".ab"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/04/13 16:46
S49	833	S48 and @ad<"20031027"	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/04/13 16:46
S50	187	S49 and aberration	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/04/13 16:46
S51	172	S50 and lithograph\$4	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/04/13 16:47

EAST Search History

S52	7	S51 and (phase same map)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/04/13 16:47
S53	126	optical lithography spatial frequency flare	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2007/09/12 16:52
S54	79	S53 and optical.ab.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2007/09/12 16:51
S55	18	S53 and (high\$3 same order same aberration)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2007/09/12 16:52
S56	106	optical lithography (spatial same frequency) flare	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	OFF	2007/09/20 18:28
S57	15	S56 and (high\$3 same order same aberration)	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	AND	ON	2007/09/12 16:52


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[Incorporation of a **phase** map into fast model-based optical **proximity** correction simulation kernels ...](#)

GM Gallatin, E Gofman, K Lai, MA Lavin, M ... - 2005 - freepatentsonline.com

... are used to create a **phase** map that ... normally ignored in traditional optical **proximity** correction (OPC ... A depicts the area for non-optimal interferometers, which ...

[Cached](#) - [Web Search](#)

[Snapshot imaging using a **FLARE** sequence. - all 3 versions »](#)

RA JONES, PA RINCK - MAGNETIC RESONANCE IN MEDICINE, 1991 - doi.wiley.com

... as the fish was in close **proximity** to the ... pulses are required and an incremental **phase** encoding scheme ... may prevent us from using an **optimum** (180° refocusing ...

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[Fast and accurate optical **proximity** correction engine for incorporating long range **flare** effects - all 3 versions »](#)

GM Gallatin, E Gofman, K Lai, MA Lavin, D Ramm, AE ... - US Patent 7,131,104, 2006 - Google Patents

... following mathematical treatment in the optical **proximity** correction engine ... using the SOCS technique, an **optimal** n^2 ... $W(a)$ is the pupil **phase** function, which ...

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[Fast and accurate optical **proximity** correction engine for incorporating long range **flare** effects](#)

K Code, GM Gallatin, E Gofman, K Lai, MA Lavin, D ... - freepatentsonline.com

... mathematical treatment in the optical **proximity** correction engine ... using the SOCS technique, an **optimal** n^2 ... over (σ) is the pupil **phase** function, which ...

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[p-mode absorption in the giant active region of 10 March, 1989 - all 5 versions »](#)

DC Braun, TL Duvall - Solar Physics, 1990 - Springer

... used in the polar grid to provide **optimal** sampling of ... It seems likely that the **proximity**

of the spot to ... for each interval9 In fact, the maximum **phase** of the ...

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[D. Montes, I. Crespo-Chacón, MJ Fernández-Figueroa, J. López-Santiago](#)

DG Alvarez, BH Foing - ucm.es

... Due to its **proximity** to the Sun (5.74pc ... that increases during the impulsive **phase**, becoming stronger... Balmer decrements (squares) and the **optimum** computed fits ...

[View as HTML](#) - [Web Search](#)

[244-nm imaging interferometric lithography - all 4 versions »](#)

A Frauenglass, S Smolev, A Biswas, SRJ Brueck - J. Vac. Sci. Technol, 2004 - chtml.unm.edu

... on-glass mask does not incorporate any optical **proximity** correction (OPC) or **phase** shift mask ... **Optimal** thicknesses as obtained from the PROLITH simulation are ...


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[J Chen](#)

[K Wampler](#)

[T Laidig](#)

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[K Harafuji](#)

A novel hierarchical approach for proximity effect correction in electron beam lithography - all 4 versions »

K Harafuji, A Misaka, N Nomura, M Kawamoto, H ... - Computer-Aided Design of Integrated Circuits and Systems, ..., 1993 - [ieeexplore.ieee.org](#)

... of the direct writing by the lithography machine is ... fast and accuracy-assuring

proximity

correction and direct ... 6] re- solves the massive **optimal** exposure dose ...

[Cited by 40](#) - [Related Articles](#) - [Web Search](#) - [BL Direct](#)

Extension of deep-ultraviolet lithography for patterning logic gates using alternating phase ... - all 4 versions »

CC Kuo, CH Lin, HT Lin, A Yen - Journal of Vacuum Science & Technology B: Microelectronics ..., 1999 - [link.aip.org](#)

Extension of deep-ultraviolet lithography for patterning ... and rule-based optical **proximity correction** (OPC) for ... Using the **optimal** process condition, a process ...

[Cited by 44](#) - [Related Articles](#) - [Web Search](#) - [BL Direct](#)

Fast Proximity Correction with Zone Sampling - all 4 versions »

J Stirniman, M Rieger - SPIE, 1994 - [spie.org](#)

Fast **proximity correction** with zone sampling Stirniman, John P ... provides accurate models of **proximity** behaviors with **optimum** computational efficiency. ...

[Cited by 51](#) - [Related Articles](#) - [Cached](#) - [Web Search](#) - [BL Direct](#)

Optical proximity correction method for intermediate-pitch features using sub-resolution scattering ... - all 4 versions »

JF Chen, K Wampler, TL Laidig - US Patent 5,821,014, 1998 - Google Patents

... and in particular relates to **proximity correction** features used ... isolated edges for **optimal proximity cor- rection** ... limit of the lithography equipment, **proximity** ...

[Cited by 72](#) - [Related Articles](#) - [Web Search](#)

System and method for preparing shape data for proximity correction - all 2 versions »

VM Chung, JB Frei, JE Stuart - US Patent 5,432,714, 1995 - Google Patents

... the art, the **optimum** focus dimension and, hence, the ... the **proximity** therebetween.

Dashed circles 20 have imity **correction** as performed by prior techniques, ...

[Cited by 71](#) - [Related Articles](#) - [Web Search](#)

Masks for improved lithographic patterning for off-axis illumination lithography - all 3 versions »

JF Chen, JA Matthews - US Patent 5,447,810, 1995 - Google Patents

... deep UV Lithography, etc. ... **Optimum** separation for scattering bars is determined empirically by ... **PROXIMITY CORRECTION AND DOF ADJUSTMENT OF ISOLATED AND DENSELY** ...

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Method and apparatus for run-time correction of proximity effects in pattern generation - all 3 versions »

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optimal proximity correction lithography higher

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TA Brunner - Journal of Research, 1997 - research.ibm.com

... off-axis illumination, and optical **proximity correction** potentially may ... not on the linewidth or **proximity** to other ... very close to that for **optimum** resist imagery ...[Cited by 63](#) - [Related Articles](#) - [Cached](#) - [Web Search](#) - [BL Direct](#)[Ringfield **lithography** - all 4 versions »](#)

TE Jewell, K Thompson - US Patent 5,315,629, 1994 - Google Patents

... x-ray radiation used in **proximity** printing is ... with conic con- stants to provide **optimal correction** and to ... are also used to provide **optimal** diffraction limited ...[Cited by 59](#) - [Related Articles](#) - [Web Search](#)[Electron beam **lithography** for 0.13 \$\mu\text{m}\$ manufacturing - all 4 versions »](#)

MA McCord - Journal of Vacuum Science & Technology B: Microelectronics ..., 1997 - link.aip.org

... Current electron beam **lithography** techniques, including shaped beam ... is suggested to as an **optimal** beam voltage ... the need for **proximity correction** but requires ...[Cited by 23](#) - [Related Articles](#) - [Web Search](#) - [BL Direct](#)[Electron optical image **correction** subsystem in electron beam projection **lithography** - all 4 versions »](#)

S Kojima, W Stickel, JD Rockrohr, M Gordon - Journal of Vacuum Science & Technology B: Microelectronics ..., 2000 - link.aip.org

... own data path in the **optimal** ways to ... pattern-specific emulation (PSE) and **proximity effect correction** ... is, architecture of the dynamic **correction** system should ...[Cited by 9](#) - [Related Articles](#) - [Web Search](#) - [BL Direct](#)[A review of ion projection **lithography** - all 4 versions »](#)

J Melngailis, AA Mondelli, IL Berry III, R ... - Journal of Vacuum Science & Technology B: Microelectronics ..., 1998 - link.aip.org

... reference plate located in close **proximity** to the ... these determined shim functions, an **optimum** set of ... In addition solenoidal magnetic **correction** fields will be ...[Cited by 36](#) - [Related Articles](#) - [Web Search](#) - [BL Direct](#)[Electron optical system for the x-ray mask writer EB-X2 - all 8 versions »](#)

K Saito, H Morita, J Kato, N Shimazu - Journal of Vacuum Science & Technology B: Microelectronics ..., 1997 - link.aip.org

... uniform field concept, and the **optimum** beam half ... **High-voltage** shaped e-beam **lithography**."J. Vac ... K. Reimer and S. Pongratz, "**Proximity correction** for electron ...[Cited by 9](#) - [Related Articles](#) - [Web Search](#) - [BL Direct](#)[Low-k optical **lithography** for 100 nm logic technology and beyond - all 4 versions »](#)

A Yen, SS Yu, JH Chen, CK Chen, TS Gau, BJ Lin - Journal of Vacuum Science & Technology B: Microelectronics ..., 2001 - link.aip.org

... must be minimized in **order** to bring out the **optimal** performance from ... and L. Van den